

<b>INFORMATION DISCLOSURE CITATION</b> <i>(Use several sheets if necessary)</i>	Docket Number (Optional) <b>NEC 2020</b>	Application Number
	Applicant(s) <b>SAEKI</b>	
	Filing Date <b>JANUARY 5, 2001</b>	Group Art Unit

**U.S. PATENT DOCUMENTS**

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE

J4821 U.S. PTO  
 09/755696  
 01/05/01

**FOREIGN PATENT DOCUMENTS**

	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
							YES	NO
D.D.		5-48354	12/24/93	JAPAN	H01J	29/94		✓
D.D.		6-9437	3/9/94	JAPAN	H01J	9/385		✓
D.D.		4298944	10/22/92	JAPAN	H01J	31/12		✓

**OTHER DOCUMENTS** *(Including Author, Title, Date, Pertinent Pages, Etc.)*

		Shimosato, Y. et al, "Vacuum Process for Plasma Display Panel without Exhaust Pipe", 1997 IDW Meeting, pps 539-542

EXAMINER

DATE CONSIDERED

2/21/03

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

